

Measurement for Nano and Micro Device
奈微米元件量測實驗
(NEMS5110)

1. The first class for course announcement starts 10:10 on **Feb. 21 (Friday), 2014.**
Please do attend. We will group students.
2. Please download the experimental manual from
Website (Link: mx.nthu.edu.tw/~chengyao).
3. General TA – Mr. Liao (廖冠勳, #80128, s9935804@m99.nthu.edu.tw)
Exp. TA – See following pages.
4. Grading: Five experimental reports and class participation (70%) and final exam (30%).
5. Lectures for all four groups: F3F4 (10:10~12:00)
Experiment:
 - 1st group: MaMb (18:20~20:10)
 - 2nd group : T9Ta (17:20~19:10)
 - 3rd group: W9Wa (17:20~19:10)
 - 4th group: R9Ra (17:20~19:10)
6. **Final exam: Jun. 20, 2014. 10:10-12:00.**
7. The deadline for homeworks: Follow lecture's instructions.

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教師 Lecture	實驗名稱 Experiment	實驗課程大綱 Syllabus	使用儀器項目 Training Tool	助教 TA
羅丞曜 C. Y. Lo	光學薄膜量測 Optical Thin Film Meas.	多層膜光學 Multilayer Optics 系統模擬 Simulation 實作 Practice	積分球儀 Integration sphere	Mr. K. Avinash #80628 kmravinash007 @gmail.com
鄭兆珉 C. M. Cheng	生化反應量測 Anal. ELISA-based Detections	酵素免疫吸附測定法 Enzyme-Linked Immunosorbent Assay 量測方式 Meas. Approach 實作 Practice	掃描器 Scanner	羅士杰 Mr. Lo #80555 roxyjay0406 @gmail.com
陳致真 C. C. Chen	DNA量測 DNA meas.	微流道系統 Microfluidics sys. 電泳系統 Electrophoretic sys.	生化分析儀 Biomedical analy.	林柏任 Mr. Lin #80636 freedomfly0710 @hotmail.com

教師
Lecture

實驗名稱
Experiment

實驗課程大綱
Syllabus

使用儀器項目
Training Tool

助教
TA

王玉麟
Y. L. Wang

半導體元件量測
Semi. dev. meas.

半導體量測介紹
Introduction
實作
Practice

半導體參數分析儀
Semiconductor
parameter
analyzer

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傅建中
C. C. Fu

微結構幾何形狀
量測實驗
Microstructure
geometry
measurement

電子顯微鏡原理
Intro. electron-
microscope
共軛焦顯微鏡
Confocal microscope

共軛焦顯微鏡
Confocal microscope

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